a third chamber capable of taking said substrate out of said multi-chamber system after depositing said gate insulating film.

83.(Amended) A multi-chamber system comprising:

a first chamber for irradiating a lamp light to a semiconductor film formed over a substrate;

a second chamber for performing at least one heating process;

a third chamber for depositing an insulating film; and

a fourth chamber capable of taking said substrate out of said multi-chamber system.

86.(Amended) A multi-chamber system comprising:

a first chamber for irradiating a laser light to a semiconductor film formed over a substrate under an atmosphere containing an oxidizing atmosphere;

a second chamber for depositing a gate insulating film on said semiconductor film;

a third chamber capable of taking said substrate out of said multi-chamber system after depositing said gate insulating film; and

a means for transporting said substrate among said first, second and third chambers.

89.(Amended) A multi-chamber system comprising:

a first chamber for irradiating a lamp light to a semiconductor film formed over a substrate;

a second chamber for performing at least one heating process;

a third chamber for depositing an insulating film;

a fourth chamber capable of taking said substrate out of said multi-chamber system;

a means for transporting said substrate among said first, second, third and fourth chambers.

92.(Amended) A multi-chamber system comprising:

a first chamber for irradiating a laser light to a semiconductor film formed over a substrate under an oxidizing atmosphere;

a second chamber for depositing a gate insulating film; and

a third chamber for putting said substrate in said multi-chamber system and for taking said substrate out of said multi-chamber system,

wherein said multi-chamber system is capable of depositing said gate insulating film on said semiconductor film irradiated with said laser light.

95.(Amended) A multi-chamber system comprising:

a first chamber for irradiating a lamp light to a semiconductor film formed over a substrate;

a second chamber for performing at least one heating process;

a third chamber for depositing an insulating film; and

a fourth chamber for putting said substrate in said multi-chamber system and for taking said substrate out of said multi-chamber system.

98.(Amended) A multi-chamber system comprising:

a first chamber for irradiating a laser light to a semiconductor film formed over a substrate under an oxidizing atmosphere;

a second chamber for depositing a gate insulating film;

a third chamber for putting said substrate in said multi-chamber system and for taking said substrate out of said multi-chamber system; and

a means for transporting said substrate among said first, second and third chambers,

wherein said multi-chamber system is capable of depositing said gate insulating film on said semiconductor film irradiated with said laser light.

101.(Amended) A multi-chamber system comprising:

a first chamber for irradiating a lamp light to a semiconductor film formed over a substrate;

a second chamber for performing at least one heating process;

a third chamber for depositing an insulating film;

a fourth chamber for putting said substrate in said multi-chamber system and for taking said substrate out of said multi-chamber system; and

a means for transporting said substrate among said first, second, third and fourth chambers.

104.(Amended) A multi-chamber system according to claim 80 wherein said laser comprises an excimer laser or a YAG laser.

105.(Amended) A multi-chamber system according to claim 80 wherein said laser light has a rectangular shape on an irradiated surface.

106.(Amended) A multi-chamber system according to claim 83 wherein said laser comprises an excimer laser or a YAG laser.

107.(Amended) A multi-chamber system according to claim 83 wherein said laser light has a rectangular shape on an irradiated surface.

108.(Amended) A multi-chamber system according to claim 86 wherein said laser comprises an excimer laser or a YAG laser.

109.(Amended) A multi-chamber system according to claim 86 wherein said laser light has a rectangular shape on an irradiated surface.

111.(Amended) A multi-chamber system according to claim 89 wherein said laser comprises an excimer laser or a YAG laser.

112.(Amended) A multi-chamber system according to claim 89 wherein said laser light has a rectangular shape on an irradiated surface.

114.(Amended) A multi-chamber system according to claim 92 wherein said laser comprises an excimer laser or a YAG laser.

115.(Amended) A multi-chamber system according to claim 92 wherein said laser light has a rectangular shape on an irradiated surface.

116.(Amended) A multi-chamber system according to claim 95 wherein said laser comprises an excimer laser or a YAG laser.

117.(Amended) A multi-chamber system according to claim 95 wherein said laser light has a rectangular shape on an irradiated surface.

118.(Amended) A multi-chamber system according to claim 98 wherein said laser comprises an excimer laser or a YAG laser.

119.(Amended) A multi-chamber system according to claim 98 wherein said laser light has a rectangular shape on an irradiated surface.

121.(Amended) A multi-chamber system according to claim 101 wherein said laser comprises an excimer laser or a YAG laser.

122.(Amended) A multi-chamber system according to claim 101 wherein said laser light has a rectangular shape on an irradiated surface.

Please add new claims 124-131 as follows:

--124.(New) A multi-chamber system according to claim 83 wherein said lamp is one selected from the group consisting of a xenon lamp, a krypton lamp, and a halogen lamp.

125.(New) A multi-chamber system according to claim 83 wherein said insulating film comprises a gate insulating film.

126.(New) A multi-chamber system according to claim 89 wherein said lamp is one selected from the group consisting of a xenon lamp, a krypton lamp, and a halogen lamp.

127.(New) A multi-chamber system according to claim 89 wherein said insulating film comprises a gate insulating film.

128.(New) A multi-chamber system according to claim 95 wherein said lamp is one